Low-pressure plasma system V240-2G
Reel-to-reel unit for etching, cleaning or activation

The reel-to-reel system V240-2G is designed for the low-pressure plasma etching of finest structures on plastic foils and is also suitable for plasma activation and cleaning processes.

The system is equipped with two special high performance etching generators and is prepared for upgrading by two additional sources (V240-4G).

The plasma process operates during winding of the substrate.

Options
• Vacuum pump
• Further gas channels
• Closed circuit cooling
• Reel tempering up to 90 °C

Technical data
Dimensions of the system (W x D x H): approx. W 2,900 x D 1,500 x H 2,170 mm
Inner dimensions process chamber (W x D x H): approx. W 1,300 x D 560 x H 770 mm
Roll diameter: max. 300 mm, substrate width: max. 350 mm, roll weight: max. 25 kg
Microwave generators: 2 pcs. à 2.45 GHz, flexible power from 200 W to 2,000 W per source
Gas supply: 3 gas channels with mass flow controllers and magnetic valves
Vacuum connection: DN 100 ISO-K
Electrical connection: 230/400 V, 50/60 Hz
Process control: PLC control unit
Vacuum gauge: capacitance manometer (independent of gas type)
Interfaces: Ethernet, USB